Lecture 6: Process Modules II

- Announcements:
- HW#2 online
- This will be our second 2-hour lecture to make up for the lecture missed previously
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- Today:
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6
  - Example MEMS fabrication processes
  - Oxidation
  - Film Deposition
    - Evaporation
    - Sputter deposition
    - Chemical vapor deposition (CVD)
    - Plasma enhanced chemical vapor deposition (PECVD)
    - Epitaxy
    - Atomic layer deposition (ALD)
    - Electroplating
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 4, 5
  - Lithography
  - Etching
    - Wet etching
    - Dry etching
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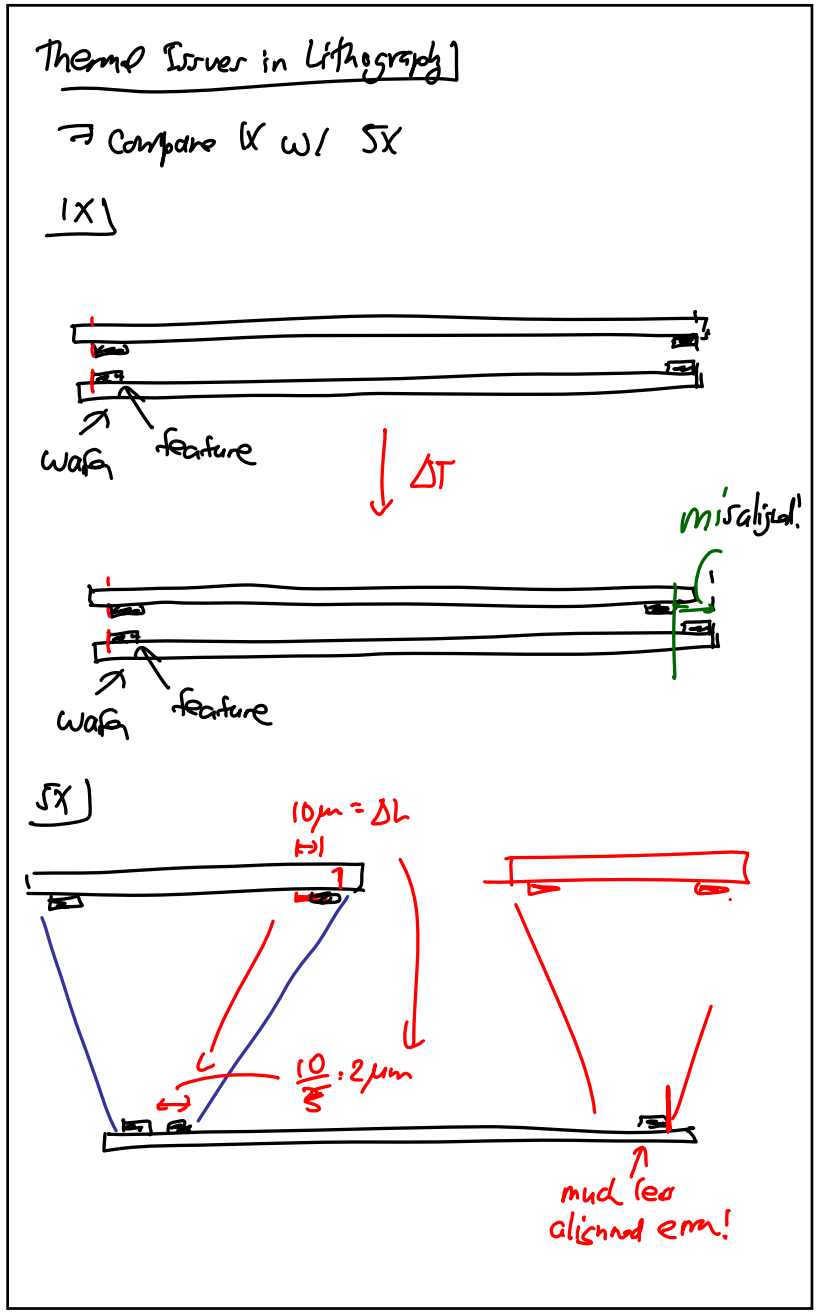
- Last Time: going through Module 3
- Continue doing this …
- … then start Module 4



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